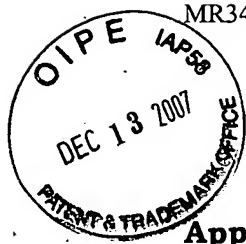


IFW



MR347-44

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Appl. No. : 10/674,153**  
**Applicant : KUO-HUANG HSIEH (Inventor)**  
**Filed : September 29, 2003**  
**TC/A.U. : 1762**  
**Examiner : LIN, JAMES**

**For: Micro-Stamping Method for Photoelectric Process**

**AMENDMENT AND RESPONSE**

Mail Stop Amendment

Honorable Commissioner for Patents

P.O. Box 1450

Alexandria VA 22313-1450

Sir:

The Examiner issued a non-final Office Action dated 14 June 2007 in the above-referenced Patent Application. In the Office Action, the Examiner set a three month shortened statutory period for reply. That reply period having now expired, a Request and fee for a three month Extension of Time is concurrently filed herewith to ensure timely filing.

This paper is in response to the Official Action filed 14 June 2007. Kindly amend the above-identified application as follows:

**AMENDMENTS TO THE CLAIMS** are reflected in the listing of claims which begins on page 2 of this paper.

**REMARKS/ARGUMENTS** begin on page 4 of this paper.